

No.1**Procurement of Electron Microscope (SEM and TEM)**

Amendment number	Reference in Tender documents	Original text	Amendment (new text)
1.	Technical Specifications 2.1	<p>The SEM must be a Field Emission Scanning Electron Microscope (FESEM), with a high brightness gun capable of delivering:</p> <ul style="list-style-type: none">• Landing voltage range of 20 eV to 30 keV, continuously variable• A beam current ≥ 100 nA	<p>The SEM must be a Field Emission Scanning Electron Microscope (FESEM), with a high brightness gun capable of delivering:</p> <ul style="list-style-type: none">• Landing voltage range of 20 eV to 30 keV or 100 eV to 30 kV, continuously variable• A beam current ≥ 100 nA



2.	<p>Technical Specifications</p> <p>2.22</p>	<p>The microscope should come with an Energy Dispersive X-ray system.</p> <p>EDS system with 30 mm² SDD (Peltier cooled) EDS detector with ≤ 129 eV resolution on Mn Kα, with integrated FET to provide excellent performance at low and high count rates (Input count rates > 1,000,000 cps; Output count rates > 300,000 cps)</p> <p>EDS analyser system must provide spectral imaging (acquisition of a spectrum at every pixel of the electron image) complete with raw and net (quantitative) mapping real-time during acquisition. Following software options also must be included:</p> <ul style="list-style-type: none"> • Drift compensation software • Library match software <p>Real-time (during acquisition) phase mapping based on advance statistical analysis software employing the algorithms developed by Paul Kotula at Sandia National Labs and defined in US Patents 6,684,413 and 6,675,106 and explained in Microscopy and Microanalysis 12 (2006) pp 36-38, 538-544</p>	<p>The microscope should come with an Energy Dispersive X-ray system.</p> <p>EDS system with 30 mm² SDD (Peltier cooled) EDS detector with ≤ 129 eV resolution on Mn Kα, with integrated FET to provide excellent performance at low and high count rates (Input count rates > 1,000,000 cps; Output count rates > 300,000 cps)</p> <p>EDS analyser system must provide spectral imaging (acquisition of a spectrum at every pixel of the electron image) complete with raw and net (quantitative) mapping real-time during acquisition. Following software options also must be included:</p> <ul style="list-style-type: none"> • Drift compensation software • Library match software
3.	<p>Section VI.</p> <p>1. Related Services and Completion Schedule</p>	<p>1. Delivery period will commence on the date of the advance payment. If the bidder does not require an advance payment implementation period will commence at the entry into force of the Contract Agreement (signing of the contract and submission of the Performance Guarantee) - 90 (ninety) days.</p>	<p>1. Delivery period will commence on the date of the advance payment. If the bidder does not require an advance payment implementation period will commence at the entry into force of the Contract Agreement (signing of the contract and submission of the Performance Guarantee) :</p> <p>SEM 150 (hundred and fifty) days and, TEM 210 (two hundred and ten) days.</p>

The Public Procurement Commission

